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NEW DEVELOPMENTS AND APPLICATIONS IN DUAL BEAM

SI will describe two patented technologies, recently developed using the FIB-SEM equipment at LMA. The first technology uses focused electron beam induced deposition to grow magnetic tips [1], of application in magnetic resonance force microscopy, scanning nanowire magnetic force sensing and magnetic force microscopy. The second technology, focused ion beam induced deposition under cryogenic conditions [2], allows the growth of deposits with growth-speed enhancement up to 600 times, and can be used for circuit editing and for the growth of electrical contacts at the micro/nano-scale. [1] Jaafar et al., Nanoscale 12, 10090 (2020); [2] De Teresa et al., Micromachines 10, 799 (2019)

SPEAKER

José María De Teresa

José María De Teresa is research professor at the Institute of Nanoscience and Materials of Aragon. After a Ph.D. at U. Zaragoza, he got postdoctoral positions at IFW-Dresden and CNRS-Paris. He coordinates the Spanish network on Nanolithography and he chairs the Condensed Matter Division Board in the European Physical Society. His main research interests are nanofabrication with focused electron/ion beams and its application to nanoelectronics, magnetic materials, and nano-superconductors.

We invite you to attend this webinar APRIL 15, 2021, 12:00 ZOOM WEBINAR: <u>HTTPS://BIT.LY/3CGUJDN</u>







